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PTO/SB/08A (08-03)

Approved for use through 7/31/2006. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1 of 5

Complete if Known

APPLICATION NUMBER	10/789,319
FILING DATE	02/27/2004
FIRST NAMED INVENTOR	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Office	Number ⁴				

mz	B1	2002/0177319	A1	Chou	11/28/2002		
	B2	6,518,189	B1	Chou	2/11/2003		
	B3	6,828,244	B2	Chou	12/7/2004		
	B4	6,809,356	B2	Chou	10/26/2004		
	B5	2004/0197843	A1	Chou et al.	10/7/2004		
	B6	2004/0156108	A1	Chou et al.	8/12/2004		
	B7	2004/0137734	A1	Chou et al.	7/15/2004		
	B8	2004/0131718	A1	Chou et al.	7/8/2004		
	B9	2004/0118809	A1	Chou et al.	6/24/2004		
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	B11	2003/0080472	A1	Chou	5/1/2003		
	B12	2003/0034329	A1	Chou	2/20/2003		
	B13	2002/0042027	A1	Chou et al.	4/11/2002		
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	B16	5,629,095		Bujanowski et al.	5/13/1997		
	B17	5,861,467		Bujanowski et al.	1/19/1999		
mz	B18	5,331,020		Brown et al.	7/19/1994		

Examiner
Signature

Marc Zimmer

Date
Considered

6/2/05

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Sheet	2	of	5	Attorney Docket Number	P121-63-03

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mg	B19	4,617,238		Crivello et al.	10/14/1986	
	B20	6,580,172	B2	Mancini et al.	6/17/2003	
	B21	10/948,511		Xu et al.	9/23/2004	
	B22	10/967,740		Xu et al.	10/18/2004	
	B23	10/919,062		Xu et al.	8/16/2004	
	B24	4,512,848		Deckman et al.	4/23/1985	
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	B29	5,601,641		Stephens	2/11/1997	
	B30	5,849,209		Kindt-Larsen et al.	12/15/1998	
mg	B31	5,849,222		Jen et al.	12/15/1998	

Examiner Signature	Marc Zimmer	Date Considered	6/2/05
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ms	B32	WO	02/07199		Chou	1/24/2002		
	B33	WO	2004/114016		Chou et al.	12/29/2004		
	B34	WO	99/05724		Chou et al.	2/4/1999		
	B35	WO	03/010289		Chou et al.	2/6/2003		
	B36	WO	03/079416		Chou	9/25/2003		
ms	B37	WO	03/099536		Chou et al.	12/4/2003		

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Sheet 4 of 5				Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²

mf	B38	Chou et al., Nanoimprint Lithography, Journal of Vacuum Science Technolgy B 14(16), pp. 4129-4133, 11/1/1996	
	B39	Colburn et al., Development and Advantages of Step-and-Flash Lithography, Solid State Technology, 7/1/2001	
	B40	Colburn et al., Characterization and Modeling of Volumetric and Mechanical Properties for Step and Flash Imprint Lithography Photopolymers, Journal of Vacuum Science Technology. Vol b. 19(6), 11/1/2001	
	B41	Yu et al., Properties of Fluorinated Amorphous Diamond Like Carbon Films by PECVD, Applied Surface Science 219 (3-4); pp. 228-237, 12/1/2003	
	B42	Compon et al., Electroanalysis at Diamond-Like and Doped-Diamond Electrodes, Electroanalysis 15(17); pp. 1349-1363, 9/1/2003	
	B43	Mansano et al., Protective Carbon Layer for Chemical Corrosion of Stainless Steel, Diamond and Related Materials 12 (3-7); pp. 749-752, 3/1/2003	
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mf	B46	Zhu et al., The Improvement of the Oxidation Resistance of TiAl Alloys by Fluorine Plasma-Based Ion Implantation, Surface and Coatings Technology 158; pp. 502-507, 9/1/2002	

Examiner Signature	Marc Zimmer	Date Considered	6/2/05
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²

mg	B47	Yao et al., Structural, Mechanical and Hydrophobic Properties of Fluorine-Doped Diamond-Like Carbon Films Synthesized by Plasma Immersion Ion Implantation and Deposition (PIII-D), Applied Surface Science 230; pp. 172-178, 4/17/2004	
	B48	Bailey et al., Step and Flash Imprint Lithography: Defect Analysis, Journal of Vacuum Science, B 19(6), pp. 2806-2810, 11/1/2001	
	B49	Bailey et al., Step and Flash Imprint Lithography: Template Surface Treatment and Defect Analysis, Journal of Vacuum Science, B 18(6), pp. 3572-3577, 11/1/2000	
mg	B50	Schneider et al., Stripes of Partially Fluorinated Alkyl Chains: Dipolar Langmuir Monolayers	

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mg	C5	Data Sheet for MAK (Methyl n-Amyl Ketone), www.sp-chem.com/fine_e, 1/1/2003	
	C6	Data Sheet for gamma-Glycidioxypropyltrimethoxysilane, www.powerchemical.net/3100.htm, 12/5/2003	
	C7	Silicon or Silica, www.mii.org/Minerals/photosil, 3/31/2005	
	C8	Electronic Devices and Circuits, people.deas.harvard.edu/~jones/es154/lectures/lecture_2/materials/materials.html, 3/31/2005	
	C9	Data Sheet for Cymel 303ULF, www.cytec.com, 12:00:00 AM	
	C10	Data Sheet for Cycat 4040, www.cytec.com, 12:00:00 AM	
	C11	International Chemical Safety Card for p-Toluenesulfonic Acid, www.itcilo.it/english/actrav/telearn/osh/ic/104154.htm, 12/5/2003	
	C12	Data Sheet for p-Toluenesulfonic Acid, NIOSH Manual of Analytical Methods (NMAM), Fourth Edition, 12:00:00 AM	
	C13	Data Sheet for Dow Corning Z-6018, , 12:00:00 AM	
mg	C14	Data Sheet for Methyl Amyl Ketone, www.arb.ca.gov/db/solvents/solvent_pages/Ketones-HTML/methyl_amyl.htm, 3/31/2005	

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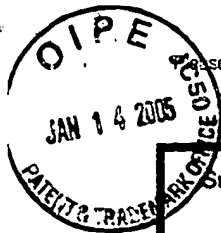
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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	COMPOSITION FOR AN ETCHING MASK COMPRISING A SILICON-CONTAINING MATERIAL						
Application Number: 10/789319 *10/789319*							
Confirmation Number: 9202							
First Named Applicant: Frank Xu							
Attorney Docket Number: P121-63-03							
Art Unit: 1712							
Examiner: Marc S. Zimmer							
Search string: (5737064).pn.							
US Patent Documents							
Note: Applicant is not required to submit a paper copy of cited US Patent Documents							
init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
<i>mf</i>	1	5737064	1998-04-07	Inoue et al.			
Signature							
Examiner Name				Date			
<i>Marc Zimmer</i>				<i>6/2/05</i>			



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		Number	Kind Code ² (if known)			
ms	A1	3,527,062		Belinski et al.	09-08-1970	
	A2	3,783,520		King	01-08-1974	
	A3	3,807,027		Heisler	04-30-1974	
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	A7	4,070,116		Frosch et al.	01-24-1978	
	A8	4,098,001		Watson	07-04-1978	
	A9	4,119,688		Hiraoka	10-10-1978	
	A10	4,155,169		Drake et al.	05-22-1979	
	A11	4,201,800		Alcom et al.	05-06-1980	
	A12	4,202,107		Watson	05-13-1980	
	A13	4,267,212		Sakawaki	05-12-1981	
	A14	4,326,805		Feldman et al.	04-27-1982	
	A15	4,337,579		De Fazio	07-06-1982	
	A16	4,355,469		Nevins et al.	10-26-1982	
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	A18	4,426,247		Toshiakai et al.	01-17-1984	
	A19	4,440,804		Milgram	04-03-1984	
	A20	4,451,507		Beltz et al.	05-29-1984	
	A21	4,507,331		Hiraoka	03-26-1985	
	A22	4,544,572		Sandvig et al.	10-01-1985	
	A23	4,552,832		Blume et al.	11-12-1985	
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	A25	4,600,309		Fay	07-15-1986	
	A26	4,610,442		Oku et al.	09-09-1986	
	A27	4,657,845		Frechet et al.	04-14-1987	
	A28	4,692,205		Sachdev et al.	09-08-1987	
	A29	4,694,703		Routson	09-22-1987	
	A30	4,707,218		Giammarco et al.	11-17-1987	
	A31	4,724,222		Feldman	02-09-1988	
	A32	4,731,155		Napoli et al.	03-15-1988	
	A33	4,737,425		Lin et al.	04-12-1988	
	A34	4,763,886		Takei	08-16-1988	
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m3	A35	4,772,878		Kane	09-20-1988	
	A36	4,808,511		Holmes	02-28-1989	
	A37	4,826,943		Ito et al.	05-02-1989	
	A38	4,846,931		Gmitter et al.	07-11-1989	
	A39	4,848,179		Ubhayakar	07-18-1989	
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	A44	4,891,303		Garza et al.	01-02-1990	
	A45	4,908,298		Hefferon et al.	03-13-1990	
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	A47	4,919,748		Bredbenner et al.	04-24-1990	
	A48	4,921,778		Thackeray et al.	05-01-1990	
	A49	4,929,083		Brunner	05-29-1990	
	A50	4,931,351		McColgin et al.	06-05-1990	
	A51	4,959,252		Bonnebat et al.	09-25-1990	
	A52	4,964,145		Maldonado	10-16-1990	
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	A54	4,976,818		Hashimoto et al.	12-11-1990	
	A55	4,980,316		Huebner	12-25-1990	
	A56	4,999,280		Hiraoka	03-12-1991	
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	A59	5,071,694		Uekita et al.	12-10-1991	
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	A61	5,073,230		Maracas et al.	12-17-1991	
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A63	5,108,875		Thackeray et al.	04-28-1992		
A64	5,110,514		Soane	05-05-1992		
A65	5,126,006		Cronin et al.	06-30-1992		
A66	5,148,036		Matsugu et al.	09-15-1992		
A67	5,148,037		Suda et al.	09-15-1992		
A68	5,151,754		Ishibashi et al.	09-29-1992		
Examiner Signature	Marc Zimmer				Date Considered	6/2/05

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			Application Number	10/789,319	
			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
			Group Art Unit	1712	
Examiner Name	Zimmer, Marc S.				
Attorney Docket Number	P121-63-03				
Sheet	3	of	25		

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document ²	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ³ (if known)			
m3	A69	5,155,749		DiMilia et al.	10-13-1992	
	A70	5,169,494		Hashimoto et al.	12-08-1992	
	A71	5,171,490		Fudim	12-15-1992	
	A72	5,173,393		Sezi et al.	12-22-1992	
	A73	5,179,863		Uchida et al.	01-19-1993	
	A74	5,198,326		Hashimoto et al.	03-30-1993	
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	A78	5,218,193		Miyatake	06-08-1993	
	A79	5,234,793		Sebald et al.	08-10-1993	
	A80	5,240,550		Boehnke et al.	08-31-1993	
	A81	5,240,878		Fitzsimmons et al.	08-31-1993	
	A82	5,242,711		DeNatale et al.	09-07-1993	
	A83	5,244,818		Jokerst et al.	09-14-1993	
	A84	5,259,926		Kuwabara et al.	09-09-1993	
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	A86	5,277,749		Griffith et al.	01-11-1994	
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	A90	5,328,810		Lowrey et al.	07-12-1994	
	A91	5,330,881		Sidman et al.	07-19-1994	
	A92	5,348,616		Hartman et al.	09-20-1994	
	A93	5,355,219		Araki et al.	10-11-1994	
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	A100	5,392,123		Marcus et al.	02-21-1995	
	A101	5,414,514		Smith et al.	05-09-1995	
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Examiner Signature	Marc Zimmer				Date Considered	6/2/05

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			Application Number	10/789,319	
			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
			Group Art Unit	1712	
			Examiner Name	Zimmer, Marc S.	
Sheet	4	of	25	Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
mg	A103	5,421,981		Leader et al.	06-06-1995	
	A104	5,422,295		CHOI et al.	06-06-1995	
	A105	5,424,549		Feldman	06-13-1995	
	A106	5,425,848		Haisma et al.	06-20-1995	
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	A109	5,439,766		Day et al.	08-08-1995	
	A110	5,452,090		Proglor et al.	09-19-1995	
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	A114	5,480,047		Tanigawa et al.	01-02-1996	
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	A118	5,512,131		Kumar et al.	04-30-1996	
A119	5,515,167		Ledger et al.	05-07-1996		
A120	5,523,878		Wallace et al.	06-04-1996		
A121	5,527,662		Hashimoto et al.	06-18-1996		
A122	5,545,367		Bae et al.	08-13-1996		
A123	5,563,702		Emery et al.	10-08-1996		
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Examiner Signature	Marc Zimmer			Date Considered	6/2/05	

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			Application Number	10/789,319	
			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
			Group Art Unit	1712	
			Examiner Name	Zimmer, Marc S.	
Sheet	5	of	25	Attorney Docket Number	P121-63-03

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		Number	Kind Code ² (if known)			
m3	A137	5,747,102		Smith et al.	05-05-1998	
	A138	5,753,014		Van Rijn	05-19-1998	
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	A152	5,884,292		Baker et al.	03-16-1999	
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A154	5,895,263		Carter et al.	04-20-1999		
A155	5,900,160		Whitesides et al.	05-04-1999		
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A158	5,926,690		Toprac et al.	07-20-1999		
A159	5,937,758		Maracas et al.	08-17-1999		
A160	5,942,871		Lee	08-24-1999		
A161	5,948,219		Rohner	09-07-1999		
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Examiner Signature	Marc Zimmer				Date Considered	6/2/05

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				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03
Sheet	6	of	25		

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m3	A171	6,046,056		Parce et al.	04-04-2000	
	A172	6,051,345		Huang	04-18-2000	
	A173	6,074,827		Nelson et al.	06-13-2000	
	A174	6,081,334		Brimbergen et al.	06-27-2000	
	A175	6,088,103		Everett et al.	07-11-2000	
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A190	6,204,922	B1	Chalmers	03-20-2001		
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A192	6,234,379	B1	Donges	05-22-2001		
A193	6,245,213	B1	Olsson et al.	06-12-2001		
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A203	6,361,831	B1	Sato et al.	03-26-2002		
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Examiner Signature	Marc Zimmer			Date Considered	6/4/05	

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Application Number	10/789,319
				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	7	of	25	Attorney Docket Number	P121-63-03

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m3	A205	6,387,783	B1	Furukawa et al.	05-14-2002	
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	A212	6,411,010	B1	Suzuki et al.	06-25-2002	
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	A221	6,495,624	B1	Brown, James F.	12-17-2002	
	A222	6,514,672	B2	Young et al.	02-04-2003	
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	A229	6,541,356	B2	Seshan	04-01-2003	
	A230	6,541,360	B1	PLAT et al.	04-01-2003	
	A231	6,561,706	B2	Singh et al.	05-13-2003	
	A232	6,565,928	B2	Sakamoto et al.	05-20-2003	
	A233	6,580,505	B1	Bareket	06-17-2003	
	A234	6,588,632	B1	Nicol	07-08-2003	
	A235	6,600,969	B2	Sudolcan et al.	07-29-2003	
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m3	A237	6,633,391	B1	Oluseyi et al.	10-14-2003	
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Examiner Signature	Marc Zimmer				Date Considered	6/2/05

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Substitute for form 1449A/PTO			Complete if Known		
			Application Number	10/789,319	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
(use as many sheets as necessary)			Group Art Unit	1712	
			Examiner Name	Zimmer, Marc S.	
Sheet	8	of	25	Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
mjs	A239	6,646,662	B1	Nebashi et al.	11-11-2003	
	A240	6,677,252	B2	Marsh	01-13-2004	
	A241	6,696,157	B1	David et al.	02-24-2004	
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A272	2003/0179354	A1	Araki et al.	09-25-2003		
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			Application Number	10/789,319	
			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
			Group Art Unit	1712	
			Examiner Name	Zimmer, Marc S.	
Sheet	9	of	25	Attorney Docket Number	P121-63-03

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		Number	Kind Code ² (if known)			
ms	A273	2003/0205657	A1	Voisin	11-06-2003	
	A274	2003/0205658	A1	Voisin	11-06-2003	
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Examiner Signature	Marc Zimmer				Date Considered	6/6/05

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				Application Number	10/789,319
				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03
Sheet	10	of	25		

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				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03
Sheet	11	of	25		

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Office ³	Number ⁴	Kind Code ⁵ (if known)				
mz	A322	DE	19648844		Muller et al.	09-18-1997		
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	A342	WO	01/63361		Heldari et al.	08-30-2001		
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	A347	WO	01/79933		Heidari	10-25-2001		
	A348	WO	01/90816		Heidari	11-29-2001		
	A349	WO	02/006902		Choi et al.	01-24-2002		
	A350	WO	02/008835		Choi et al.	01-31-2002		
	A351	WO	02/067055		Choi et al.	08-29-2002		
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	A354	WO	02/24977		Bjarnason et al.	03-28-2002		
	A355	WO	2004/006120		Watts et al.	01-15-2004		
	A356	WO	2004/016406		Sreenivasan et al.	02-26-2004		

Examiner Signature	<i>Marc Zimmer</i>	Date Considered	<i>6/6/05</i>
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Substitute for form 1449B/PTO		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	10/789,319
		Filing Date	02/27/2004
		First Named Inventor	Xu et al.
		Group Art Unit	1712
		Examiner Name	Zimmer, Marc S.
		Attorney Docket Number	P121-63-03
Sheet	13	of	25

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
mz	A367	Abstract of Japanese Patent 02-24848, January 26, 1990	
	A368	Abstract of Japanese Patent 02-92603, August 12, 2004	
	A369	Abstract of Japanese Patent 55-88332, April 14, 2004	
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<i>mj</i>	A378	BENDER et al., "Multiple Imprinting in UV-based Nanoimprint Lithography: Related Material Issues.", Microelectronic Engineering 61 - 62, January 1, 2002, pp. 407-413.	
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Examiner Signature	<i>Marc Zimmer</i>	Date Considered	<i>6/1/05</i>
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		Filing Date	02/27/2004		
		First Named Inventor	Xu et al.		
		Group Art Unit	1712		
		Examiner Name	Zimmer, Marc S.		
Sheet	15	of	25	Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
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			Application Number	10/789,319	
			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
			Group Art Unit	1712	
			Examiner Name	Zimmer, Marc S.	
Sheet	16	of	25	Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
mj	A400	GOLDFARB et al., "Compliant Micromanipulator Design for Scaled Bilateral Telemanipulation of Small-Scale Environments.", ASME International Mechanical Engineering Conference and Exposition, November 1, 1998, DSC-Vol. 64, pp. 213-218.	
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Examiner Signature	<i>Marc S. Zimmer</i>	Date Considered	<i>6/6/05</i>
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mg	A411	HOWELL et al., "A Loop-Closure Theory for the Analysis and Synthesis of Compliant Mechanisms.", Journal of Mechanical Design, March 1, 1996, Vol. 188, pp. 121-125.	
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Examiner Signature	<i>Marc Zimmer</i>	Date Considered	6/2/05
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mj	A422	KOSEKI, "Design and Accuracy Evaluation of High-Speed and High Precision Parallel Mechanism.", Proc. Of IEEE, January 1, 1998, Intl. Conf. on Robotics & Automation, pp. 1340-1345.	
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		Attorney Docket Number	P121-63-03

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mj	A433	MARTIN et al., "Predication of Fabrication Distortions in Step and Flash Imprint Lithography Templates.", Journal of Vacuum Science. B 20(6) pp. 2891-2895, November 1, 2002.	
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mj	A443	NERAC.COM Retro Search, "Trim Etching of Features Formed on an Organic Layer.", September 2, 2004.	

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mj	A444	NGUYEN, "Asymmetric Fluid-Structure Dynamics in Nanoscale Imprint Lithography." The University of Texas at Austin, August 1, 2001, pp. 1-111.	
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	A451	PAPIRER et al., "The Grafting of Perfluorinated Silanes onto the Surface of Silica: Characterization by Inverse Gas Chromatography.", Journal of Colloid and Interface Science 159, 08-01-03, pp. 238-242.	
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mj	A454	PENG et al., "Compliant Motion Control of Kinetically Redundant Manipulators.", IEEE Transactions on Robotics and Automation, December 1, 1993, Vol. 9, No. 6, pp.831-837.	

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m3	A455	PERNETTE et al., "Design of Parallel Robots in Microbotics.", Robotica, January 1, 1997, Vol. 15, pp 417-420.	
	A456	PHYSIK INSTRUMENTS, "Hexapod Six-Axis Parallel Kinematics Robot", Nano Positioning, January 1, 1998, pp. 8.4 - 8.5.	
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mz	A466	SAGIV, "Organized Monolayers by Absorption. 1. Formation and Structure of Oleophobic Mixed Monolayers on Solid Surfaces.", Journal of American Chemical Society/102:1, January 2, 1980.	
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m	A477	TAJBAKHSI et al., "Three-Degree-of-Freedom Optic Mount for Extreme Ultraviolet.", American Society for Precision Engineering, January 1, 1998, pp. 359-362.	
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m	A487	US Application No. 10/666,527, Filed 09-18-03, BAILEY et al., "Imprint Lithography Templates having Alignment Marks."	

Examiner Signature	<i>Marc Zimmer</i>	Date Considered	<i>6/2/05</i>
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Substitute for form 1449B/PTO		Complete if Known	
		Application Number	10/789,319
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Filing Date	02/27/2004
		First Named Inventor	Xu et al.
		Group Art Unit	1712
		Examiner Name	Zimmer, Marc S.
Sheet	24	of	25
		Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
mz	A488	US Application No. 10/677,639, Filed 10-02-03, MCMACKIN et al., "Single Phase Fluid Imprint Lithography Method."	
	A489	US Application No. 10/687,519, Filed 10-16-2003, TRUSKETT et al., "Low Surface Energy Templates."	
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	A494	US Application No. 10/785,248, Filed 02-24-2004, CHOI et al., "A Method to Control the Relative Position Between a Body and a Surface."	
	A495	US Application No. 10/788,700, Filed 02-27-2004, SREENIVASAN et al., "Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography."	
	A496	US Application No. 10/864,214, Filed 6-9-04, SREENIVASAN et al., "An Imprint Lithography System to Produce a Light to Impinge upon and Polymerize a Liquid in Superimposition with Template Overlay Marks."	
	A497	US Application No. 10/898,034 Filed 07-23-04, MCMACKIN et al., "A Method of Creating a Turbulent Flow of Fluid between a Mold and a Substrate."	
mz	A498	US Application No. 10/898/037, Filed 07-23-04, MCMACKIN et al., "A System of Creating a Turbulent Flow of Fluid between a Mold and a Substrate."	

Examiner Signature	Marc S. Zimmer	Date Considered	6/2/05
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Substitute for form 1449B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>			Complete if Known		
			Application Number	10/789,319	
			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
			Group Art Unit	1712	
			Examiner Name	Zimmer, Marc S.	
			Attorney Docket Number	P121-63-03	
Sheet	25	of	25		

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²	
m3	A499	US Application No. 60/394,458, Filed 07-08-2002, SREENIVASAN et al., "Method and Apparatus for Whole Wafer Planarization using Optical Flats and Light Curable Liquids."		
	A500	US Applications No. 10/616,294, Filed 07-09-2003, CHOI et al., "Systems for Magnification and Distortion Correction for Imprint Lithography Processes."		
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	A502	WANG et al., "Passive Compliance versus Active Compliance in Robot-Based Automated Assembly Systems.", Industrial Robot, January 1, 1998, Vol. 25, No. 1, pp. 48-57.		
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m3	A507	XIA et al., "Soft Lithography.", Annu Rev. Mater. Sci., 1998, 28: 153-184.		

Examiner Signature	<i>Marc Zimmer</i>	Date Considered	<i>1/16/05</i>
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Electronic Version v18

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Title of Invention

COMPOSITION FOR AN ETCHING MASK COMPRISING A
SILICON-CONTAINING MATERIAL

Application Number : 10/789319



Confirmation Number: 9202

First Named Applicant: Frank Xu

Attorney Docket Number: P121-63-03

Art Unit: 1712

Examiner: Marc S. Zimmer

Search string: (6468642 or 5542978 or 5837314 or 6565776 or 6503914 or 6649272 or 6204343
or 4614667 or 3810874 or 6737489 or 6721529 or 6664306 or 6790905 or 6544594
or 6774183 or 6830819 or 6802870 or 5389696).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
ms	1	6468642	2002-10-22	Bray et al.	B1		
	2	5542978	1996-08-06	Kindt-Larsen et al.			
	3	5837314	1998-11-17	Beaton et al.			
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	5	6503914	2003-01-07	Benish et al.	B1		
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	8	4614667	1986-09-30	Larson et al.			
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Signature

Marc Zimmer

6/13/05